WHAT IS CLAIMED IS:

1. A multibeam light source comprising:

a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam; and

a deflector that receives the laser beams and deflects the laser beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, wherein

a sub-scanning beam pitch is set as P-(A/VM)·VS+C, where P is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam pitch is defined by a distance between an arbitrary point on a line connecting focuses of a preceding array of the focuses and a point that corresponds to the arbitrary point on a line connecting focuses of an adjoining array of the focuses.

2. The multibeam light source device according to claim 1, wherein the laser beams received by the deflector have a predetermined opening angle.

3. The multibeam light source according to claim 1, wherein the recording density interval is 50 μm or less.

4. A multibeam light source comprising:

a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam; and

a deflector that receives the laser beams and deflects the laser beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, wherein

a sub-scanning beam pitch is set as $P-(A/VM)\cdot VS+C$, where P is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam pitch is defined by a distance between a most preceding array of the focuses and an adjoining array of the focuses.

5. The multibeam light source device according to claim 4, wherein the laser beams received by the deflector have a predetermined opening angle.

6. The multibeam light source according to claim 4, wherein the recording density interval is 50 μm or less.

7. A multibeam light source comprising:

a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam; and

a deflector that receives the laser beams and deflects the laser beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, wherein

a sub-scanning beam pitch is set as $P-(A/VM)\cdot VS+C$, where P is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam pitch is defined by a distance between a center of focuses of a first semiconductor laser array and a center of focuses of a second semiconductor laser array, wherein the first semiconductor laser array scans first in a main scanning direction and the second semiconductor laser array scans next in the main scanning direction.

8. The multibeam light source device according to claim 7, wherein the laser beams received by the deflector have a predetermined opening angle.

9. The multibeam light source according to claim 7, wherein the recording density interval is 50 μm or less.

10. A multibeam scanner comprising a multibeam light source including

a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam; and

a deflector that receives the laser beams and deflects the laser beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, wherein

a sub-scanning beam pitch is set as $P-(A/VM)\cdot VS+C$, where P is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam pitch is defined by a distance between an arbitrary point on a line connecting focuses of a preceding array of the focuses and a point that corresponds to the arbitrary point on a line connecting focuses of an adjoining array of the focuses.

11. A multibeam scanner comprising a multibeam light source including

a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam; and

a deflector that receives the laser beams and deflects the laser

beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, wherein

a sub-scanning beam pitch is set as P-(A/VM)·VS+C, where P is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam pitch is defined by a distance between a most preceding array of the focuses and an adjoining array of the focuses.

12. A multibeam scanner comprising a multibeam light source device including

a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam; and

a deflector that receives the laser beams and deflects the laser beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, wherein

a sub-scanning beam pitch is set as P-(A/VM)·VS+C, where P is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam

pitch is defined by a distance between a center of focuses of a first semiconductor laser array and a center of focuses of a second semiconductor laser array, wherein the first semiconductor laser array scans first in a main scanning direction and the second semiconductor laser array scans next in the main scanning direction.

13. A method of scanning used on a multibeam scanner, the multibeam scanner including a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam, and a deflector that receives the laser beams and deflects the laser beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, the method comprising:

setting a sub-scanning beam pitch as P-(A/VM)·VS+C, where P is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam pitch is defined by a distance between an arbitrary point on a line connecting focuses of a preceding array of the focuses and a point that corresponds to the arbitrary point on a line connecting focuses of an adjoining array of the focuses.

14. A method of scanning used on a multibeam scanner, the multibeam scanner including a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam, and a deflector that receives the laser beams and deflects the laser beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, the method comprising:

setting a sub-scanning beam pitch as P-(A/VM)·VS+C, where P is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam pitch is defined by a distance between a most preceding array of the focuses and an adjoining array of the focuses.

15. A method of scanning used on a multibeam scanner, the multibeam scanner including a plurality of semiconductor laser arrays, wherein each semiconductor laser array includes a plurality of semiconductor lasers each of which emits a laser beam, and a deflector that receives the laser beams and deflects the laser beams towards a recording medium, whereby an array of focuses is formed on the recording medium corresponding to each semiconductor laser array, the method comprising:

setting a sub-scanning beam pitch as P-(A/VM)·VS+C, where P

is a recording density interval on the recoding medium, VM is a main scanning velocity, VS is a sub-scanning velocity, A is an interval between the arrays of focuses in a main scanning direction, and C is a correction amount of the beam pitch, wherein the sub-scanning beam pitch is defined by a distance between a center of focuses of a first semiconductor laser array and a center of focuses of a second semiconductor laser array, wherein the first semiconductor laser array scans first in a main scanning direction and the second semiconductor laser array scans next in the main scanning direction.